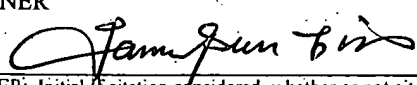


PTO-1449		Application No. Unknown 10/615,040		Applicant(s) James W. Blatchford, Jr., et al.			
Information Disclosure Citation In an Application		Docket Number: TI-35516 (032350.B504)		Group Art Unit Unknown 2025			
		U.S. PATENT DOCUMENTS					
		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	A						
	B						
	C						
	D						
	E						
	F						
	G						
	H						
	I						
	J						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
							YES NO
	K						
	L						
	M						
	N						
		DOCUMENT (Including Author, Title, Source, and Pertinent Pages)					DATE
	O	FringeSoft, Zernike and Seidel Polynomials, Zernike polynomials, http://www.fringesoft.com/siedel.htm ; copyright 2000 FringeSoft; 2 pages.					June 28, 2000
	P	Gennari, Frank E., "Validation of the aberration pattern-matching OPC strategy," Design, Process Integration, and Characterization for Microelectronics, Alexander Starikov, Kenneth W. Tobin, Jr., Editors, Proceedings of SPIE Vol. 4692, pages 444-453.					2002
	Q	Calibre OPC and PSM, Manufacturability Datasheet, "Calibre OPC and PSM: Enabling Silicon Accuracy, Speed and Yield from 180nm to 65nm," Mentor Graphics, Mentor Graphics Corporation, www.mentor.com/dsm , 6 pages.					April 2003
	R						
EXAMINER 				DATE CONSIDERED 11-03-04			
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.							

U.S. PATENT AND TRADEMARK OFFICE